INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 110.01100101	Serial No.: 10/019,521
	Applicant: Peter J. Schiller	Confirmation N .: 2112
	Filing Date: December 27, 2001	Group: Unassigned
	Information Disclosure Statement mailed:	August 15, 2002

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
JJ	—	4,784,721	11/15/88	Holmen et al.	216	2	—
JJ	—	4,996,082	02/26/91	Guckel et al.	427	99	—
JJ	—	5,209,119	05/11/93	Polla et al.	73	723	—
JJ	—	5,332,469	07/26/94	Mastrangelo	216	2	—
JJ	—	5,438,875	08/08/95	Fung et al.	73	721	—
JJ	—	5,466,932	11/14/95	Young et al.	250	299	—
JJ	—	5,656,778	08/12/97	Roszhart	73	504.04	—
JJ	—	5,672,551	09/30/97	Fung	438	53	—
JJ	—	5,707,077	01/13/98	Yokota et al.	280	735	—
JJ	—	5,725,785	03/10/98	Ishida et al.	216	2	—
JJ	—	5,802,684	09/08/98	Fujiu et al.	29	25.35	—
JJ	—	5,831,162	11/03/98	Sparks et al.	73	504.12	—

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation Yes	Translation No
JJ	—	DE 42 27 819 A1	02/25/93	Germany	—	—	x	
JJ	—	JP 2-33974	05/02/90	EPO (with English language abstract)	—	—	x	
JJ	—	JP 09 237903 A	09/09/97	Japan (with English language abstract)	—	—		x
JJ	—	WO 01/00523 A1	01/04/01	PCT	—	—	N/A	

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial		Document Description
JJ	—	Catling, "High-sensitivity silicon capacitive sensors for measuring medium-vacuum gas pressures," *Sensors and Actuators A,* 1998; *64*:157-164.

EXAMINER	Date Considered
Jason Stoll	10/21/03

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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JS	—	French, "Development of surface micromachining techniques compatible with on-chip electronics," *J. Micromech. Microeng.,* 1996; *6*:197-211.
JS	—	Fung et al., "Multifunction Polysilicon Pressure Sensors for Process Control," *Sensors,* 1999 Oct.; *16*(10):75-79, 83.
JS	—	Kwon et al., "Three Axis Piezoresistive Accelerometer Using Polysilicon Layer," *Transducers '97,* International Conference on Solid-State Sensors and Actuators, Chicago, Ill., June 16-19 1997; 1221-1188.
JS	—	Lee et al., "Piezoelectric Cantilever Microphone and Microspeaker," *J. of Microelectromechanical Systems,* 1996 Dec.; *5*(4):238-242.
JS	—	Lemkin et al., "A 2-Axis Force Balanced Accelerometer Using a Single Proof-Mass," *Transducters '97,* International Conference on Solid-State Sensors and Actuators, Chicago, Ill., 1997; 1185-1224.
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JS	—	Pedersen et al., "An integrated silicon capacitive microphone with frequency-modulated digital output," *Sensors and Actuators A,* 1998; *69*:267-275.
JS	—	Wolf et al., *Silicon Processing for the VLSI Era,* Sunset Beach, Calif. Lattice Press, Lattice Press, Sunset Beach, Cali., 1986, Cover Page, Publication Page, and Table of Contents only. (12 pgs.)
JS	—	Yazdi et al., "An All-Silicon single-wafer fabrication technology for precision microaccelerometers," *Transducters '97,* International Conference on Solid-State Sensors and Actuators, Chicago, Ill., 1997; 1181-1184.
JS	—	Yeh et al., "A Low-Voltage Tunneling-Based Silicon Microaccelerometer," *IEEE Transactions on Electron Devices,* 1997 Nov.; *44*(11):1875-1882.

EXAMINER	Date Considered
Jessie	10/21/03

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